IAP20 REC'S POT/PTO 21 DEC 2005

Sheet <u>1</u> of <u>1</u>

Substitute Form PTO-1449 U.S. Department of Commerce (Modified) Patent and Trademark Office		Attorney's Docket No. 17979-034US1		
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Shafer et al.		
		Filing Date Herewith	Group Art Unit	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
WC ^	AA	US2003/174408	9/18/2003	Rostalski Hans- Juergen et al.			
	AB	US2005/024609	2/3/2005	De Smit et al.			
	AC	US2005/074704	4/7/2005	Endo et al.			
	AD	US2005/0179877	8/18/2005	Mulkens et al.			
Ψ	AE	US2005/0219707	10/6/2005	Schuster et al.			

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner	Desig.	Document Number	Publication	Country or			Trans	lation
Initial	ID	Number	Date	Patent Office	Class	Subclass	Yes	No
WC	AF	WO2005/006026	1/20/2005	WIPO				
	AG	WO2005/081067	9/1/2005	WIPO				
	AH	EP0291596B1	1/19/1994	EPO				
	AI	WO2005/059645	6/30/2005	WIPO				
	AJ	WO2005/059618	6/30/2005	WIPO				
	AK	WO2004/019128	3/4/2004	WIPO				
V	AL	WO2005/031823	4/7/2005	WIPO				

	Other Documents (include Author, Title, Date, and Place of Publication)					
Examiner	Desig.					
Initial	ID	Document				
WC	AM	Hoffnagle, J.A. et al. "Liquid immersion deep-ultraviolet interferometric lithography", Journal of Vacuum Science & Technology B: Microelectronics Processing and Phenomena, American Vacuum Society, New York, NY, US, vol. 17, no. 6, November 1999 (1999-11), pages 3306-3309				
\downarrow	AN	Smith, et al. "Water-based 193nm immersion lithography", online, 28 January 2004, retrieved from the internet: <u>URL:http://www.sematech.org/resources/litho/meetings/immersion/20040128/presentations/06%20 RIT%20microstepper%20efforts Smith.pdf</u> , retrieved on 2005-05-24				
	AO					
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Examiner Signature /William Choi/	Date Considered 02/23/2007
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